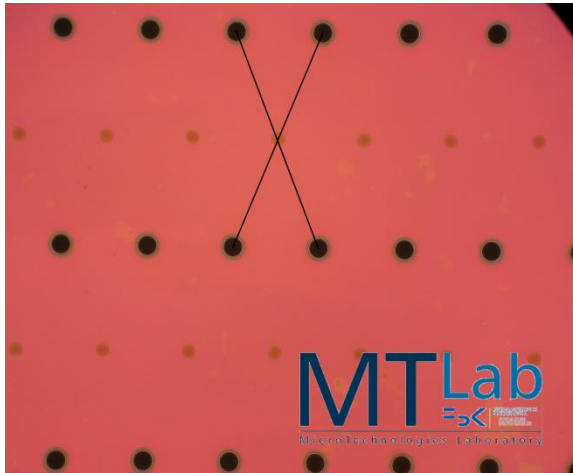


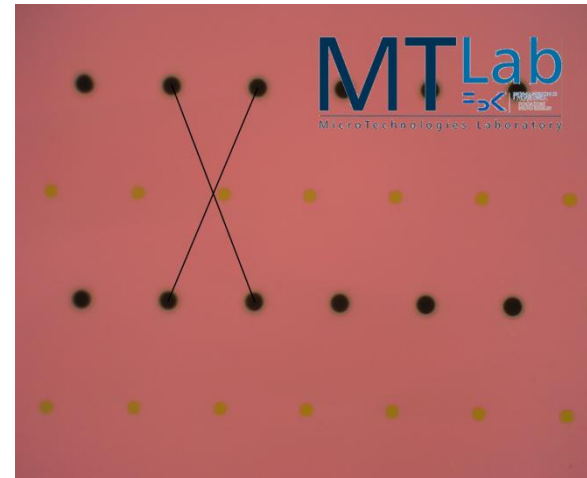
ATLAS07 (old process)

The curvature of the wafer made alignment quality vary across the wafer: misalignment is clearly observed at the edge of the wafer while the centre of the wafer is well aligned

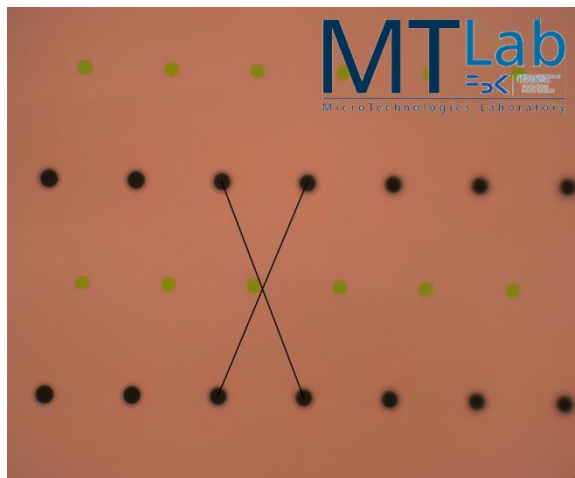
center of the wafer



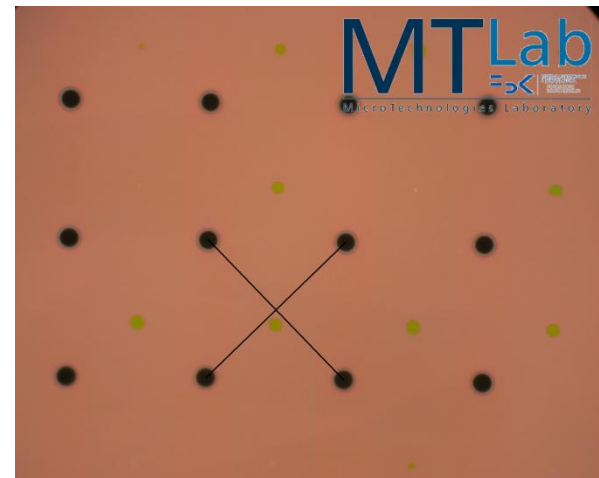
less than 1cm from the right edge



less than 1cm from the left edge

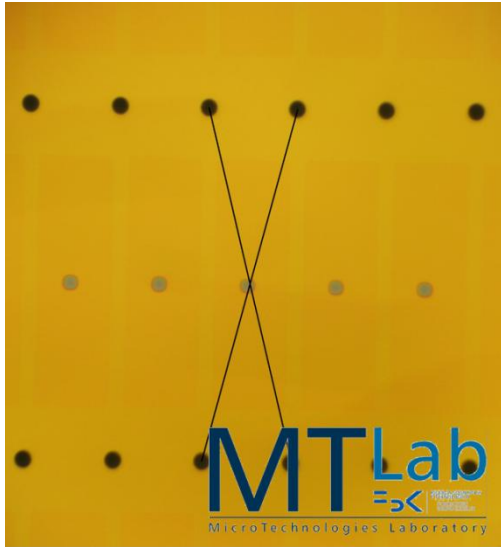


less than 1cm from the bottom edge

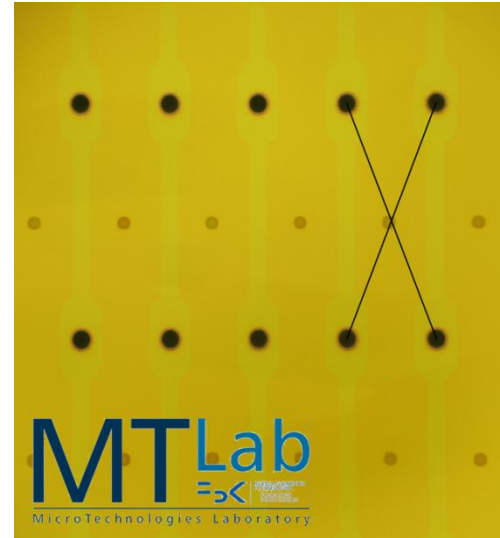


ATLAS08 (new process)

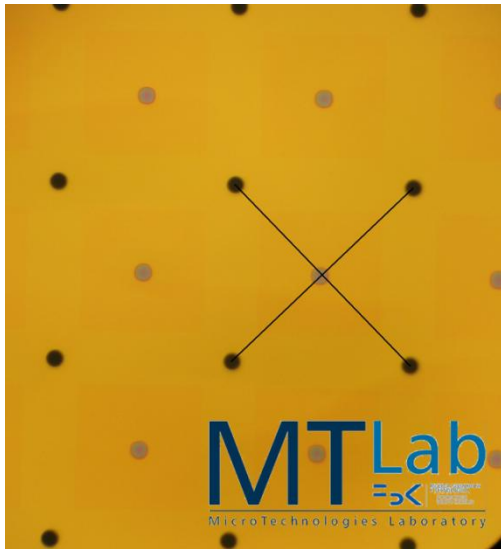
better alignment



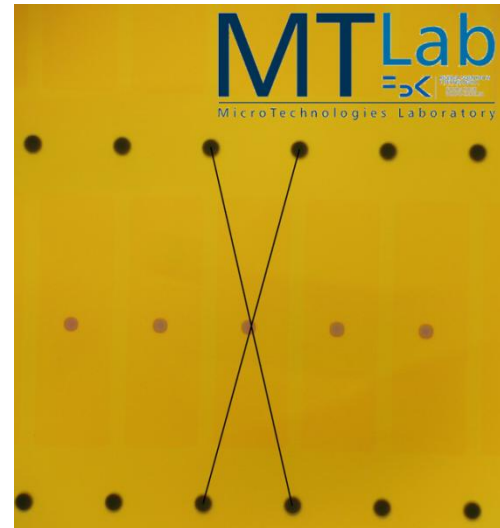
less than 1cm from the top edge



less than 1cm from the bottom edge



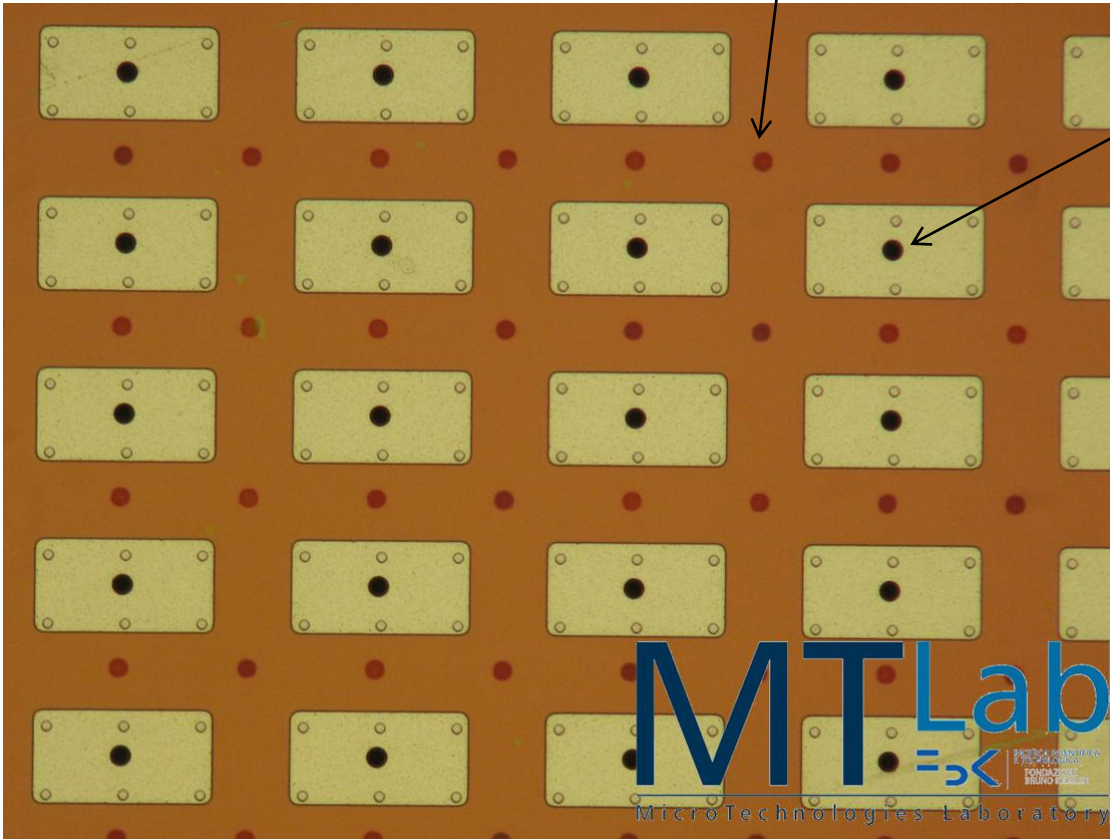
less than 1cm from the right edge



center of the wafer

p+ holes

n+ holes



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